

First results on NUV-SiPMs at FBK

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We show selected results on the first release of **Near Ultra Violet SiPM technology (NUV-SiPM)** produced at FBK. The PDE in the near-UV part of the light spectrum is mainly limited by the quantum efficiency term since the photo-generation takes place in a very shallow region of the silicon. Thus, besides using a p+-on-n junction configuration to have an avalanche triggered by the electrons, we need to implement a very shallow p+ layer.

20 °C

0 °C

-20 °C

6

5

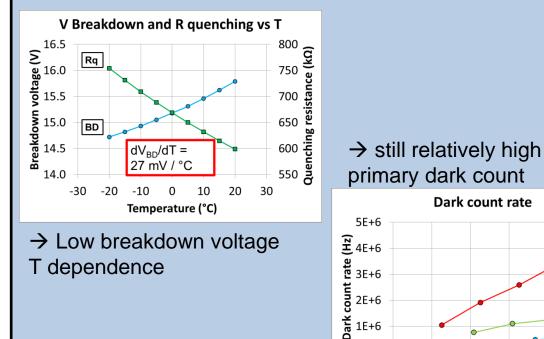
Functional measurements on 1x1 mm² 50 µm cell NUV SiPM

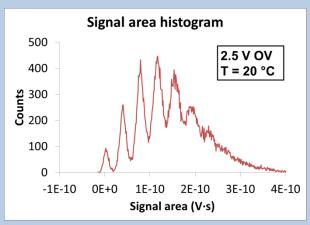
0E+0

0

1

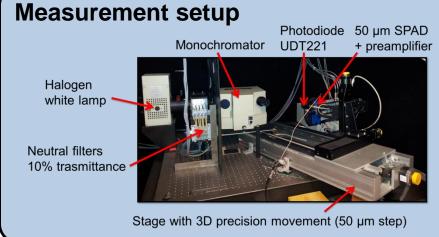
Over-voltage (V)





→ good single cell
response uniformity
(peak resolution mainly
limited by electronic noise)

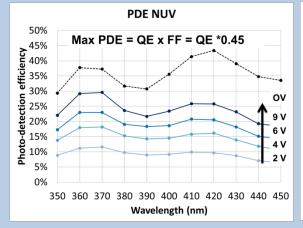




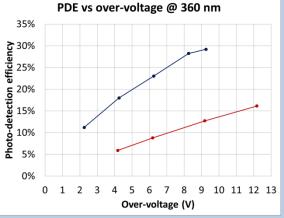
A SPAD (with same SiPM cell layout) is used to have lower noise and eliminate any cross-talk.

Pulse rate is extracted from the histogram of the time difference between consecutive pulses. Only events falling on Poisson statistic are counted to eliminate after-pulse contribution!!

NUV SiPM PDE and comparison with n-on-p technology



QE measured on test photo-diode allows us to evaluate max PDE (higher plot). PDE=30% is measured at 360 nm, 9 V OV.



In NUV SiPM PDE increases faster with OV w.r.t STD since the avalanche is triggered by electrons instead of holes. **Conclusions:** We presented the first results of the NUV-SiPM produced at FBK. The functional measurements on a 1x1mm² 50x50um² SiPM show that the device is working properly. The optical characterization of a SPAD with the same cell structure of the SiPM evidences a PDE as high as 30% at 360nm and 9 V overvoltage which is a rather good value considering a FF=45%. We are currently working to improve the noise and after-pulse performance of this new technology.

